

INFORMATION DISCLOSURE CITATION IN AN APPLICATION (Use several sheets if necessary) PTO Form 1449	Atty Docket No. 113197-020	Application No. Unknown
	Applicant Yamamoto, S., et al.	
	Filing Date January 14, 2002	Group Unknown



U.S. PATENT DOCUMENTS							
Examiner's Initials	Document Number	Publication Date	Inventor	Class	Subclass	Filing Date If Appropriate	
MAH	3,993,939	11-23-76	Slavin et al.				
MAH	4,092,696	5-30-78	Boesen et al.				
MAH	4,823,230	4-18-89	Tiemann				
MAH	4,831,492	5-16-89	Kuisma				
MAH	4,838,088	6-13-89	Murakami				
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FOREIGN PATENT DOCUMENTS							
Examiner's Initials	Document Number	Publication Date	Country	Class	Subclass	Translation	
MAH	11-326095	11-26-99	Japan			Yes	No

Examiner's Initials	OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)
MAH	Seidel, H., et al., "Anisotropic Etching of Crystalline Silicon in Alkaline Solutions," J. Electrochem, Soc., Vol. 137, No. 11, November 1990, pp. 3626-3632.

Examiner: <i>Marcia Jeger</i>	Date Considered: <i>10/1/02</i>
*Examiner: Initial if citation considered, whether or not citation is in conformance with PEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	